IN THE UNITED STATES POTENT AND TRADEMARK OFFICE

Patent Application Serial No	
Filing Date	
Inventor	
Assignee	Micron Technology, Inc
Group Art Unit	
Examiner	
Attorney's Docket No	MI22-2246
Customer No	
Title Wet Etching Method	of Removing Silicon From a Substrate

## SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References - See Attached Form PTO-1449

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449. No admission is made regarding whether all the submitted references are prior art.

This Supplemental Information Disclosure Statement is being filed before the mailing of a first office action after the filing of a Request for Continued Examination. Therefore, no fee is believed to be required. However, in the event that a fee is required for filing this Supplemental Information Disclosure Statement, please charge the fee specified under 37 C.F.R. § 1.17(p) to Deposit Account No. 23-0925.

Respectfully submitted,

Dated: 98-06

Mark S. Markin Reg. No. 32,268

Form PTO-1449 U.S. DEPARTMENT OF COMMERCE ATTY, DOCKET NO. SERIAL NO .: PATENT AND TRADEMARK OFFICE 10/625,166 MI22-2246 LIST OF ART CITED BY APPLICANT (Use several sheets if necessary) APPLICANT: Janos Fucsko et al. FILING DATE **GROUP ART UNIT:** July 22, 2003 2813 **U.S. PATENT DOCUMENTS** Document Date Class Subclass Filing Date \*Examiner's Initials Number If Appropriate 3,434,896 03/25/69 Chance AB 03/24/92 Takemura et al. 5,099,304 10/18/05 6,955,972 B2 Lee et al. AD ΑE AG ΑН Al FOREIGN PATENT DOCUMENTS Class Subclass Date Country Translation Document Number ΑK OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.) AO DATE CONSIDERED **EXAMINER** \*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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